

Abstract Of The Disclosure

A method for manufacturing a micromechanical pressure sensor and a pressure sensor manufactured using this method. The pressure is measured in the pressure sensor composed of at least two components via a capacitance measurement of a capacitor, the pressure sensor having at least one first electrode and one first diaphragm. The movement of the diaphragm causes a change in the capacitance of the capacitor which may be used in the capacitance measurement as a measure for the pressure variable to be measured. It is important that, prior to assembly, the first and the second components of the pressure sensor be processed separately. The first component has at least one semiconductor material and the first electrode, whereas the second component is made of metal, at least in part, and contains at least the first diaphragm.